

HB LED

Production processes and tools for HB LED manufacture offering exceptional Batch and Single Wafer capability

Oxford Instruments offers a unique family of process solutions for high brightness LED production, ensuring the highest possible throughput at key points in the production process

Family of batch production solutions

System133

PECVD Batch Deposition

- Load locked system enabling deposition of doped and undoped passivation on 22 x 2" and 5 x 4" batch sizes.

800Plus

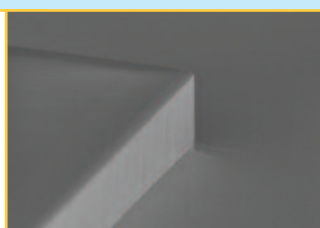
PECVD Batch Deposition

- Production scale PECVD of passivation layers in a large batch open-loading configuration.
- SiN_x and SiO₂ deposition across batches of 48 x 2" and 11 x 4" wafers.

System133 ICP380

ICP Batch Etch

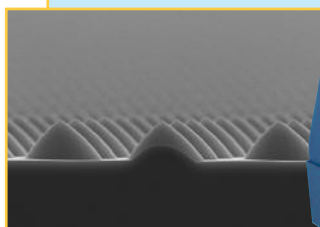
- Production solution offering superb batch etch capability for high throughput.
- Sapphire etching 18 x 2" and 5 x 4", GaN etching 27 x 2" and 5 x 4", AlGaN etching 20 x 2" and 5 x 4".



AlGaN Etching: 20 x 2" and 5 x 4" batch or single wafer



GaN Etching: 27 x 2" and 5 x 4" batch or single wafer



Sapphire Etching: 18 x 2" and 5 x 4" batch or single wafer



800Plus

Excellent single wafer production solutions

High throughput is maintained for single wafer, through the application of advanced technologies and processes.

System100Pro ICP380

ICP Etch

Electrostatic Clamping for GaN and Sapphire substrates giving enhanced etch rates with Photoresist mask

ICP CVD and PECVD

Fast deposition rates of high quality SiN_x and SiO₂. ICP CVD offers passivation at low temperatures with low damage



System133 ICP380

Proven Cassette to Cassette handling technology with full wafer tracking is available for both single wafer and multi-wafer platen configurations.

The Business of Science[®]



World leading HBLEED Etch & Deposition Processes

- Over 10 years experience as leading supplier of equipment to HBLEED manufacturers globally
- Industry leading batch sizes
- Specifically developed systems to meet HBLEED manufacturing challenges
- Superb uniformity and repeatability
- Proven e-chuck clamping capability
- Excellent reliability and low cost of ownership



Cost of ownership & global customer support

Oxford Instruments is committed to supporting our customers' success. We recognise that this requires world class products complemented by world class support. Our global service force is backed by regional offices, offering rapid support wherever you are in the world.

We work with our customers to create the right system, process, and support package to meet your specific requirements, so our range of Service Level Agreements (SLA) will be tailored to your needs.

This can include:

- Guaranteed response times for support engineer visits and technical hotline calls
- Choice of support coverage up to 24/7
- Scheduled preventative maintenance calls
- Managed spares inventory options, including customer dedicated stock, via our parts locations worldwide
- Preferential spare part pricing
- Process training
- Certified maintenance training courses for customer's own engineers in preventative maintenance and first level troubleshooting



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- Plasma Etch & Deposition
- Atomic Layer Deposition
- Ion Beam Etch & Deposition
- Nanoscale Growth System
- HVPE Tools & Substrates

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